BEST AVAILABLE COPY

The Delphion Integrated View: INPADOC Record

Title:

Country:
Kind:

Inventor:

Assignee:

Published / Filed:

Application Number:

IPC Code:

ECLA Code:

Priority Number:

Abstract:

TW0455938B: WAFER POLISHING STOP DETECTION METHOD AN POLISHING STOP DETECTION DEVICE

TW Taiwan
B Patent

IDE, SATORU; , Japan
TANAKA, KIYOSHI; , Japan
ITO, TOSHIHIRO; , Japan

NIKON KK, Japan
News, Profiles, Stocks and More about this company

Sept. 21, 2001 / Dec. 9, 1999

TW1999088121563

H01L 21/304; B24B 37/04;

None

Dec. 10, 1998 **JP1998000368466**

A wafer polishing stop detection method and polishing stop detection device which provides the method for detecting CMP polishing stop by polishing surface status index of polishing wafer in more precision. The solution of the wafer polishing stop detection method is irradiating the light from the light source; collecting the reflection on the color recognition sensor using fiber optics for light color component recognition; recognizing the color components of the tracing material on the pre-polished wafer using the color recognition sensor; displaying an ""on"" status if the color components are recognized and an ""off"" status if the color components are not recognized; digitally displaying the ""on"" and ""off"" periods on the horizontal axis during wafer polishing from a point (except the center) on the rotating wafer surface irradiated by the color recognition sensor; detecting the integral (&Sgr;m) for the specified period for ""off"" pulse width in digital display so that when the detected integral (&Sgr;m) can be consistent with the integral value (&Sgr;n) for the specified period for ""off"" pulse width of predetermined best wafer polishing stop, defining it as the wafer polishing stop.

BEST AVAILABLE COPY

? Family:

Buy PDF	Publication	Pub. Date	Filed	Title
	US6342166B1	Jan. 29, 2002		
	US6342166	Jan. 29, 2002	Dec. 6, 1999	Method of detecting end point of p wafer and apparatus for detecting polishing
	TW0455938B	Sept. 21, 2001	Dec. 9, 1999	WAFER POLISHING STOP DETE METHOD AND POLISHING STOP DEVICE
	KR0048040A	July 25, 2000	Dec. 9, 1999	METHOD FOR DETECTING POLI POINT OF WAFER AND APPARA DETECTING THE POLISHING EN
	JP2000183002A2	June 30, 2000	Dec. 10, 1998	METHOD AND DEVICE FOR DET WAFER POLISH END-POINT

5 family members shown above

? Other Abstract Info:

DERABS G2000-486551

Inquire Regarding Licensing

C·H·I RESEARCH INC. Business Intelligence Reports

Click Here to order Patent Plaques

Gallery of Obscure Patents

Nominate this for

© 1997-2003 Thomson Delphion Research Subscriptions | Privacy Policy | Terms & Conditions | Site Map | Contact